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UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **ONO, Toshiaki et al.**

Serial No.: **09/883,922**

Group Art Unit: **1765**

Filed: **June 20, 2001**

Examiner: **ANDERSON, Matthew A.**

Confirmation No.: **3735**

For: **METHOD OF MANUFACTURING EPITAXIAL WAFER AND METHOD OF PRODUCING SINGLE CRYSTAL AS MATERIAL THEREFOR**

Attorney Docket No.: **010789**
Customer Number: **38834**

POWER TO FILE CORRECTED

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Date: September 24, 2004

Sir:

The undersigned, attorney of record in the above-identified application, hereby instructs Jamie Locklear and Element Patent Drafting, to correct the drawings, as required and approved in such above-identified application and to file such corrected formal drawings in the United States Patent and Trademark Office in such application.

In the event that this paper and such formal drawings are not timely filed, Applicants respectfully petition for an appropriate extension of time. The fees for such an extension or any other fee which may be due with respect to this paper may be charged to Deposit Account No. 50-2866.

Respectfully submitted,

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